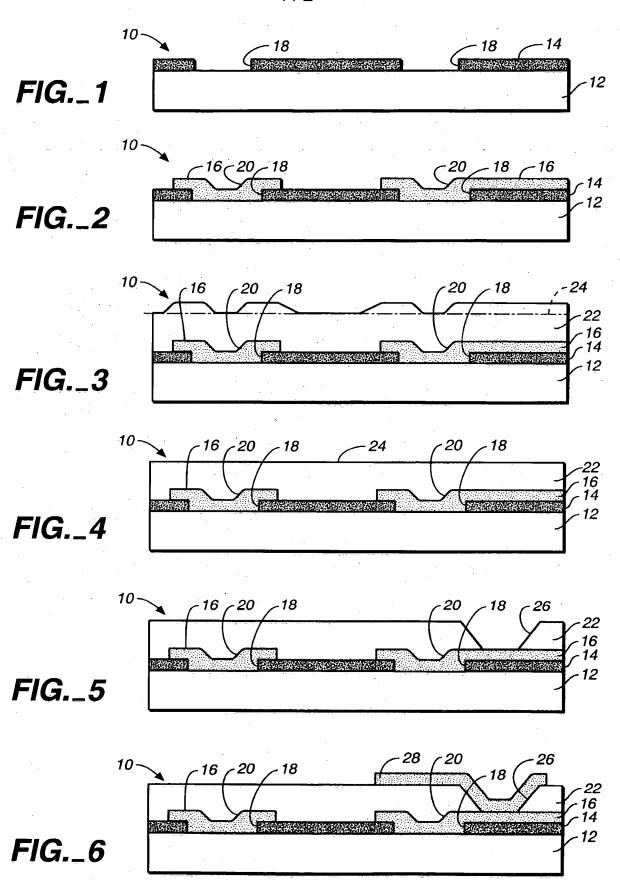
METHOD AND APPARATUS FOR DETECTING BACKSIDE CONTAMINATION DURING FABRICATION OF A SEMICONDUCTOR WAFER Michael J. Berman et al. 31692-73091/LSI-01-965/1D

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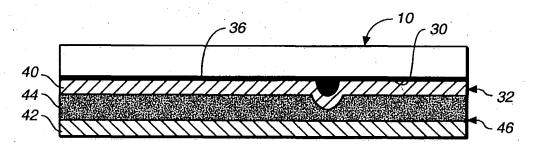


FIG.\_8

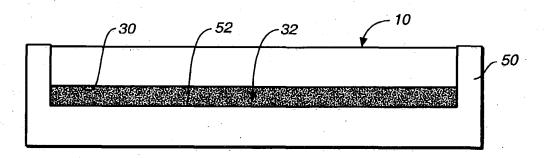


FIG.\_9